





Sectoral Operational Programme "Increase of Economic Competitiveness" *"Investments for Your Future"* 



ht Infrastructure – Nuclear Physics (EL



## ELI-NP GAMMA BEAM SYSTEM: NEW FACILITY FOR NUCLEAR PHYSICS RESEARCH – CURRENT STATUS

November 16th , 2016 University of Applied Sciences, Brugg/Windisch, Switzerland PIOTR TRACZ PIOTR.TRACZ@ELI-NP.RO FOR THE ELI-NP TEAM

### **ELI-NP Gamma Beam System**





19/03/2014

## Gamma Beam System – Basic Concept



Compton backscattering between a relativistic electron bunch and a high power laser pulse.



## Gamma Beam System – Basic Concept



Compton backscattering between a relativistic electron bunch and a high power laser pulse.



### Low cross section (~ 10<sup>-25</sup> cm<sup>2</sup>)

 $\rightarrow$  need of high density of electron and photon beams

- ¤ good and controllable monochromaticity,
- ¤ easy tunability,
- ¤ higher collimation
- ¤ full control of the gamma photon polarization.

## Gamma Beam System – Basic Concept



< 0.2 %

32

16 ns

Compton backscattering between a relativistic electron bunch and a high power laser pulse.



Energy jitter pulse-to-pulse

# pulses per macro-pulse

Pulse-to-pulse separation

 $\rightarrow$  need of high density of electron and photon beams

## **ELI-NP-GBS Electron Accelerator**



### Electron beam parameters at Interaction Points

Energy	up to 720 MeV
Bunch charge	250 pC
Bunch length	1 ps
Norm. transverse emittance	o.4 mm∙mrad
Bunch energy spread	0.04 ÷ 0.1 %
Focal spot size	~ 15 µm
Number of bunches	32
Bunch-to-bunch distance	16 ns
Energy variation along macro-bunch	0.1%
Energy jitter shot to shot	0.1%
Time arrival jitter	< 0.5 ps
Pointing jitter	ıμm
Bunch rep rate	100 Hz

### We need:

- a) high brightness (high charge, low emittance, low energy spread) and high phase space density electron beam carrying 250pC per bunch in bunch trains of 32 bunches per RF pulse, focused down to spot sizes of about 15µm.
- b) laser beam of high intensity, very brilliant, high repetition rate.

The Gamma Beam System is based on warm RF linac operated at C-band with S-band photo-injector.





**Ti:sapphire laser for photocathode RF gun** Output: ~10ps pulse duration in UV range (266nm), 150µJ/pulse, sequence of trains made of 32 pulses separated by 16ns @100Hz rep. rate.

# **Yb:YAG lasers for Interaction Points** with 3.5 ps pulse duration (FWHM) at 515 nm, 0.2J, 100Hz, 0.1% (rms) bandwidth, and pulse energy stability of 1%.









Waveguide dumping system => excited dipole modes propagate and dissipate into RF loads



#### Photo-cathode RF Gun



C-band linac –

12 x TW acc. structures

Effective damping

### 1.6-cell standing-wave RF cavity, working in S-band at 2.856 GHz.



high gradient: 120 MV/m; 100Hz photo-cathode: OFHC Copper

#### S-band injector – 2 x TW accelerating structures

Dual-symmetric feeding – min. of multipole effects. Long bunch at the photo-cathode  $(10ps) \Rightarrow$  to control the emittance growth due to space charge effects. S-band injector – reduction of the bunch length (1ps) by the velocity bunching technique.





D.Alesini et al., "Design and RF Test of Damped C-band Accelerating Structures for the ELI-NP Linac"

## **Laser Recirculation at Interaction Points**





Support Table (LBC.TS)

## **ELI–NP Facility Concept**





## **ELI–NP Facility**





## **Building Acceptance**



June-September 2016

Vibration Measurements – Gerb Engineering GmbH

Laser tracker 3D scanning for check the real dimensions and volumes of the rooms. Location of all openings etc.

Electrical measurements – grounding parameters, short-circuit current, grid voltage monitoring.

Tests of BMS, Ventilation System, Alarm system etc.



## **RF power distribution**





Stage I – delivery and tests of system components corresponding to gamma beam energy min. 1MeV (by November 2015) Components were completed with the ELI-NP label numbers, and documented with photographs.

Attachment to Addendum 3 - End of Stage 1 deliveries.xlsx 2 Equipment Description Location AMPLITUDE (Lisses) EXT Photocathode laser - 1 pulse UV EXT 1 IP Laser AMPLITUDE (Posso EXT Consolle COSYL Attachment to Addendum 3 - End of Stage 1 deliveries.xlsx FXT 11x CPU Control COSYL FXT COSYL Ethernet Converter EXT Ethernet switch COSYL Equipment Descriptio Location EXT Fanout COSYL 52 M1 Directional coupler RI (Bonn) EXT COSYL 53 M1 Waveguides S-band, T pumping 8 Monito M1 RF window EXT PLO COSYL Attachment to Addendum 3 -M1 Ion pump 20 l/s 55 10 EXT COSYL Module Equipment Description Digitize 56 M1 Ion pump 75 l/s 103 M3 Cold cathode vacuum gauge - Agilent IMG300 11 COSYL FYT 1 event generator Timing Central Station 57 M1 Pump # Module Equipment Description 104 M3 Ion pump 75 l/s 12 EXT 11 event receiver Timing Central Station COSYL 58 M1 Pump 154 M4 Quadrupole vacuum chamber 271-10651 105 M3 13 FXT Low Energy IP laser Transport line LAL (C 59 M2 H Corrector Type B1 Single plane 155 M4 4 way cross DN40 106 M3 M4 14 EXT Photocathode Laser Transport line LAL (C 60 M2 H Corrector Type B1 Single plane 156 Agilent vacuum gauge controller 107 M M2 Power Supply 157 M4 Cold cathode vacuum gauge - Agilent IMG 108 MB 61 Synchronization Main Enclosure MENL 15 EXT 158 M4 Thermal conductivity vacuum gauge - Agil Module 109 110 MB 62 M2 Power Supply MENI 16 FXT OMO related electronics 159 M4 Cold cathode vacuum gauge - Agilent IMG Cold cathode vacuum gauge - Agilent IMG300 M2 1 Solenoid Power Supply M3 103 M3 63 160 M4 Ion pump 75 I/s 104 MB Ion pump 75 I/s 17 FXT SFLspools and related electronics MENL 111 M3 M2 Power Supply Ion pump 75 I/s 105 M3 161 M4 Ion pump 75 I/ 112 мз 18 EXT SFL terminations and front end devices MENL M2 Power Supply 162 M4 106 MB Ion pump 75 I/s Ion pump 75 l/s 113 мэ M2 Solenoid B (12 coils) 107 Pumping & Vent valve (MANUAL) 19 M1 **BPM** Libera channel INFN ( 66 163 M4 Ion pump 75 l/s M3 114 M3 M2 V Corrector Type B1 Single plane 108 M3 Sector Vacuum valve (PNEUMATIC) 67 M4 20 M1 BPN INFN ( 164 Tee DN40 115 MB 109 Power Supply for 4 ION pumps M3 Directional coupler M4 M2 V Corrector Type B1 Single plane 165 68 21 M1 FCT INFN ( 116 M4 110 M3 1 T pumping S-band M2 166 M4 Pumping & Vent valve (MANUAL) 69 Girder 111 117 M4 M3 Waveguide 5-band 22 M1 INFN ( Screen chamber 167 M4A 140 MeV Beam Dump 70 M2 Mechanical support 112 M3 118 M4 1 RF window 168 M4A Screen chamber 23 M1 Screen chambe INFN ( M2 S-band Accelerating Structure 113 M3 1 Ion pump 71 119 M4 169 M4A DN63CF Ceramic break 63,5 mm tube /8k 114 M3 MSB3 (Modulator 24 M1 H & V Corrector Magnet Type A - Hor. coil INFN ( 72 M2 2 Loads (section termination) 120 M4 M4A Mechanical Support 170 115 M3 MSB3 (Klystron) 73 M2 Directional couple 121 M4 25 M1 Steerer Power Supply INFN ( 171 M4A Vacuum chamber 271-10652 116 BPM Libera chanr 122 M4 74 M2 Ion pump 75 l/s 26 M1 Solenoid Power Supply INFN ( 172 M4A Ion pump 75 l/s 117 M4 BPM Libera channel M2 4 channels Power Suppl 123 M4 118 M4 MCB1 (Modulator 27 M1 Steerer Power Supply INFN ( 124 M4 119 M4 MCB1 (Klystron) M2 76 Directional couple 125 28 M4 120 M4 DELL R220 EPICS Vacuum IO M1 INEN ( Solenoid A (2 coils) 77 M2 1 T pumping S-ban 126 M4 121 M4 BPM 29 M1 H & V Corrector Magnet Type A - Vert. coil INFN ( 78 M2 Waveguide S-band 122 M4 BPM 127 M4 30 M1 INFN ( 79 M2 1 Pump 123 124 M4 M4 BPM Girder 128 M4 80 M2 1 RF window Screen chamber 31 M1 Mechanical Support INFN ( 129 M4 125 M4 Screen chamber 81 M2 MSB2 (Modulator) 130 M4 32 M1 Vacuum chamber INEN ( 126 M4 Screen chamber M2 MSB2 (Klystron) M 82 131 127 M4 Dipole A Cold cathode vacuum gauge - Agilent IMG300 33 M1 INFN ( 83 M3 **BPM Libera channe** 132 M4 128 M4 H & V Corrector Magnet Type C - Hor, coil 34 M1 Cold cathode vacuum gauge - Agilent IMG300 INFN ( 133 M4 129 M3 M4 H & V Corrector Magnet Type C - Hor, coi 134 35 M1 Thermal conductivity vacuum gauge - Agilent TC536 Pirani INFN ( 85 M3 M4 130 M4 Magnet Power Supply Screen chambe 135 M4 131 M4 Steerer Power Supply H Corrector Type B2 Single plane M3 36 M1 Cold cathode vacuum gauge - Agilent IMG300 INFN ( 86 136 132 M4 Steerer Power Suppl M4 87 M3 H Corrector Type B2 Single plane 133 37 M1 M4 Magnet Power Supply Thermal conductivity vacuum gauge - Agilent TC536 Pirani INFN ( 137 M4 88 M3 Steerer Power Supply 134 M4 Magnet Power Suppl 138 M4 38 M1 lon pump 75 l/s INEN ( 89 M3 Steerer Power Supply 135 M4 Magnet Power Supply 139 M4 39 M1 Ion pump 75 I/s INFN ( 136 137 M4 Steerer Power Suppl 90 M3 Steerer Power Supply 140 M4 M4 Steerer Power Supply 40 M1 4 channels Power Supply (for 4 pumps) INFN ( 91 M3 Steerer Power Supply 141 M4 138 M4 QUAD Type D M3 V Corrector Type B2 Single plan 41 M1 INFN ( 92 142 M4 Pump Power Supply 139 M4 QUAD Type D M3 V Corrector Type B2 Single plane 143 M4 140 M4 QUAD Type I 42 M1 INFN ( Residual gas analyse 94 M3 144 M4 141 M4 H & V Corrector Magnet Type C - Vert. coil Girde M1 43 Pumping & Vent valve (MANUAL) INFN ( 142 M4 H & V Corrector Magnet Type C - Vert. coil 145 N44 95 M3 Mechanical suppor 44 M1 Pumping & Vent valve (MANUAL) INFN ( 143 M4 Girder 146 M4 M3 Directional coupler 96 144 147 M4 Mechanical Support 45 M1 Sector Vacuum valve (PNEUMATIC) INEN ( M4 97 M3 S-band Accelerating Structure 145 M4 DELL R220 EPICS Magnet IO 148 M4 46 M1 Sector Vacuum valve (PNFUMATIC) INEN ( M3 146 M4 C-band Accelerating Structure 98 2 Loads (section termination) 149 M4 147 544 RF loads for C1 47 M1 **RF** window RI (Be 99 M3 Vacuum chambers 150 M4 148 Transverse Deflecting Cavity M4 100 M3 Cold cathode vacuum gauge - Agilent IMG300 48 M1 S-band RF Gun cavity RI (Bo 151 M4 149 M4 Direction Coupler C band 101 M3 Thermal conductivity vacuum gauge - Agilent RF pumping tee waveguide for C band 152 M4 150 M4 49 M1 MSB1 (Modulator) RI (Bo 102 M3 Cold cathode vacuum gauge - Agilent IMG300 151 M4 RF pumping tee waveguide for TDC01 153 M4 50 MSB1 (Klystron) RI (Bo

51 M1 **Directional couple** 

RI (Bo

1/4

![](_page_14_Picture_3.jpeg)

STFC (Daresbury

STEC (Daresbury)

STFC (Daresbury

152 M4

153

RE waveguide elbow for C1

Dipole A Vacuum chamber 271-10278

Nuclear Physics

Photo-gun

![](_page_15_Picture_1.jpeg)

### INFN, Frascati, Italy

Modules M1, M2, M3 (components mounted and aligned with laser tracker) Every module is completed with horizontal and vertical steerers for beam position adjustment, beam position monitor system (BPM) and screens for beam profile analysis, vacuum elements, power supplies

![](_page_15_Figure_4.jpeg)

![](_page_15_Figure_5.jpeg)

### STFC, Daresbury, UK

Provided two modules M4 and M4A (mounted components and aligned with laser tracker)

M4 – C-band accelerating structure, 3x quadrupole magnets and a dipole magnet. M4A – beam dump.

Every module is completed with horizontal and vertical steerers for beam position adjustment, beam position monitor systems (BPM) and OTR screens for beam profile analysis, vacuum elements (gauges, ion pumps, manual an automatic valves), power supplies.

(Stage II – modules M5 to M8 were in advanced stage of mounting.)

![](_page_15_Figure_11.jpeg)

![](_page_16_Picture_1.jpeg)

### Scandinova, Uppsala, Sweden

 Modulators and klystrons – modulators MSB1, MSB2, MSB3, MCB1

![](_page_16_Picture_4.jpeg)

### Research Instruments, Bonn/Bergish Gladbach, Germany

- Power conditioning of S- and C-band accelerating structures, and photo-gun
- Photo-gun, S-band structures, RF waveguides, vacuum components, directional couplers, RF windows.
- RI will install RF components in the ELI-NP building,
- Takes care of the implementation of the network of reference points for the accelerator alignment in the ELI-NP building.

![](_page_16_Picture_10.jpeg)

### Menlo Systems, Munich, Germany

- Timing systems for synchronization at femtoseconds level
- Timing distribution needed to synchronize the electron beam and the laser pulses at the interaction point with an accuracy better than 500fs.
- The system is based on Optical Master Oscillator and Stabilized Fiber Links, ensuring the synchronization of the RF and laser systems.

### Cosylab, Ljubljana, Slovenia

- Delivery of the software and hardware necessary to control the modules M1 to M4

![](_page_17_Picture_1.jpeg)

### ACP Systems, Amplitude Systems, France

Interaction laser IP1 – delivery of configuration able to provide pulses of  $100\mu$ J at 100Hz repetition rate and 515nm wavelength.

![](_page_17_Figure_4.jpeg)

### Amplitude Technologies, Lisses, France

Photocathode laser: stretcher, 100Hz regenerative amplifier, 100Hz multipass pre-amplifier, 2 x 100Hz multi-pass amplifiers, compressor, pump lasers.

Tests of module were successful being able to produce the 32 pulses separated at 16ns with an intensity fluctuations below 5%.

### LAL CNRS, Orsay, France

Laser beam transport lines for photocathode laser and IP1.

![](_page_17_Picture_10.jpeg)

![](_page_18_Picture_0.jpeg)

## **Thank You for Your Attention**

## www.eli-np.ro

## **ELI–NP High Power Laser System**

![](_page_19_Picture_1.jpeg)

![](_page_19_Figure_2.jpeg)

## Extreme Light Infrastructure (ELI)

![](_page_20_Picture_1.jpeg)

the world's first international laser research infrastructure

pan–European distributed research infrastructure based presently on 3 facilities in CZ, HU and RO

### **ELI–Beamlines, Prague, CZ**

High–Energy Beam Facility development and application of ultra–short pulses of high–energy particles and radiation

ELI-ALPS, Szeged, HU Attosecond Laser Science Facility new regimes of time resolution

ELI–NP, Magurele, RO Nuclear Physics Facility with ultra–intense laser and brilliant gamma beams (up to 20 MeV) novel photonuclear studies

## **ELI Roadmap**

![](_page_21_Picture_1.jpeg)

![](_page_21_Figure_2.jpeg)

**ELI Delivery Consortium** 

## Photo-gun laser

![](_page_22_Picture_1.jpeg)

![](_page_22_Figure_2.jpeg)

## **Interaction Points Lasers**

![](_page_23_Picture_1.jpeg)

**High Energy Interaction** 

2 x 0.2

515

3.5

100

≤ 1.2

28

0.1%

1

< 1ps

1%

![](_page_23_Figure_2.jpeg)

Interaction Lasers: cryo-cooled Yb:YAG

	/		
		A.D.	
		200	
. 3.			

![](_page_24_Picture_1.jpeg)

### Simulated gamma beams for different energies

Photon Energy [MeV]	2.00	3.45	9.87	19.5
# photons / shot within FWHM bdw.	$< 1.2 \cdot 10^{5}$	$< 1.1 \cdot 10^{5}$	$< 2.6 \cdot 10^{5}$	$< 2.5 \cdot 10^{5}$
# photons / sec within FWHM bdw.	$< 4.0 \cdot 10^{8}$	$< 3.7 \cdot 10^{8}$	$< 8.3 \cdot 10^{8}$	$< 8.1 \cdot 10^{8}$
Source rms size [µm]	12	11	11	10
Source rms divergence [µrad]	≤140	$\leq 100$	$\leq$ 50	$\leq$ 40
Pulse length (rms) [ps]	0.92	0.91	0.95	0.90

### **GBS** Linac

![](_page_25_Picture_1.jpeg)

High quality gamma beam -> requires high quality electron beam

![](_page_25_Figure_3.jpeg)

## **Electron Gun**

![](_page_26_Picture_1.jpeg)

### **Gun sector - module 1**

Laser-driven photocathode 1.6-cell standing-wave RF cavity, working in S-band at 2.856 GHz.

Photocathode – (oxygen-free high thermal conductivity) OFHC Copper

![](_page_26_Picture_5.jpeg)

### <u>Ti:Sa laser</u>-

**output:** UV range (266nm), 10ps, 150µJ/pulse, sequence of trains made of 32 pulses separated by 16ns @ 100Hz repetition rate.

![](_page_26_Figure_8.jpeg)

![](_page_26_Picture_9.jpeg)

Photo-gun laser parameters at cathode:

Laser pulse length (flat-top)	10 [ps]	
Laser pulse rise/fall time FWHM	0,7 [ps]	
Energy per pulse at 266 nm	150µJ	
Laser spot size RMS radius on cathode	100-400 [µm]	
Laser pulse energy jitter	2%	
Time arrival jitter	<0.5 [ps]	
Pointing jitter	<20 [µm]	

### Electron beam parameters:

Beam energy	5.7 [MeV]
Bunch charge	250 [pC]
Bunch length	~10 [ps]

## S-band injector

![](_page_27_Picture_1.jpeg)

![](_page_27_Figure_2.jpeg)

due to space charge effects.

S-band injector – reduction of the bunch length by the velocity bunching technique.

Dual-symmetric feeding structures – minimization of the multipole effects generated by asymmetric feeding.

Beam loading effects - compensated with modulation of input RF power. No evidence of HOM dipole modes in experimental measurements.

![](_page_27_Figure_7.jpeg)

Fig. 10: reflection coefficient at the input port after tuning

## **C-band LINAC**

![](_page_28_Picture_1.jpeg)

![](_page_28_Figure_2.jpeg)

## Laser Recirculation at IP

![](_page_29_Picture_1.jpeg)

![](_page_29_Figure_2.jpeg)

 High damage threshold optics, high level of cleanness and high vacuum required K.Dupraz et al., Phys.Rev. STAB 17 (2014) 033501

## **Gamma Beam Collimation and Diagnostics**

![](_page_30_Picture_1.jpeg)

### Collimator System to obtain narrow bandwidth main requirements are:

- Low transmission of gamma photons (high density and atomic number)
- **Continuously adjustable aperture** (to adjust the energy bandwidth in the entire energy range)
- Avoid contamination of the primary beam with production of secondary radiation

Collimation aperture varies from 20mm to less than 1mm

Tungsten slits – 20 mm thick

Low-energy configuration: 12 independent slits with 30° relative angle

High-energy configuration: 14 independent slits with 25.7° relative angle

![](_page_30_Figure_10.jpeg)

Gamma Beam Diagnostic System for:
γ Beam characterization
energy, intensity, profile

### **Collimator System**

![](_page_30_Picture_13.jpeg)

## **Timing and Synchronization System**

![](_page_31_Picture_1.jpeg)

![](_page_31_Figure_2.jpeg)

Timing and synchronization system layout

**RMO** -  $\mu$ -wave crystal oscillator with ultra-low phase noise characteristics **OMO** – highly stable fiber-laser oscillator that encodes the reference timing information in the repetition rate of short optical pulse in the IR spectrum Ultra-stable reference signal will be distributed to the clients through actively stabilized links. The stability of each link is  $\approx$ 70fs over any time scale. Each individual clients will be locked to the local reference provided by the timing distribution systems. MENLO

Together with a continuous reference signal, low repetition rate trigger signals must be provided to some clients, which contain essentially the information on the timing of the macro pulses needed to prepare all the systems to produce and monitor the bunches and the radiation pulses (laser amplification pumps, klystron HV, bema diagnostics,....) The triggering system is a coarser timing line ( $\approx$ 10ps stability, that can be distributed either optically or electrically. COSYLAB (MRF)

![](_page_31_Figure_6.jpeg)

![](_page_31_Picture_7.jpeg)

## **Timing and Synchronization System**

![](_page_32_Picture_1.jpeg)

#### Master clock Stabilized fiber link Phase error mixer The reference signal is gen transmitted to the end users b The phase error is measured the laser oscillator and one error is used to drive actuate high frequency piezo-electric stepper motor driven optical of

#### Laser systems synchronization

The reference signal is generated by an optical master oscillator (OMO) and transmitted to the end users by a stabilized fibre optic link.

The phase error is measured by optical mixing (cross-correlator). One pulse from the laser oscillator and one from the OMO overlap. The measured phase noise error is used to drive actuator to active control the oscillator's cavity length -> high frequency piezo-electric transducer (PZT) is associated to a lower frequency stepper motor driven optical delay line.

![](_page_32_Figure_6.jpeg)

Fig. 104. Sketch of the ELI-NP single power station

### Synchronization of the RF clients

RF driving signal for all power sources will be locally extracted from the OMO reference transported to each station by stabilized phase links. The optical to electrical conversion will be accomplished by photodiodes. The same reference is used to demodulate various RF pulses sampled over the network, and the whole station is rephased in real time on the base of the measured values.

## **ELI–NP Nuclear Physics Research**

![](_page_33_Picture_1.jpeg)

![](_page_33_Figure_2.jpeg)